



Docket No. MIT7941

AF/1700

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Yong-Pil Han et al.  
Serial No.: 09/498,303  
Filed: February 4, 2000  
For: HF VAPOR PHASE WAFER CLEANING AND OXIDE ETCHING

Group Art Unit: 1763  
Examiner: T. Dang

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ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, DC 20231

I hereby certify that this correspondence is being deposited on the date shown below with the United States Postal Service with sufficient postage as first class mail, under 37 CFR 1.8(a), in an envelope addressed to:  
Assistant Commissioner For Patents,  
Washington, D.C. 20231

*Theresa A. Lober*  
April 3, 2003

#9  
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MW

**PETITION FOR THREE -MONTH EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)**

Hereby is petitioned the Assistant Commissioner for Patents to extend for the patent application referenced above the period for response to the Examiner's Action mailed October 7, 2002, for three (3) months, extending the last day of the response period from January 7, 2003, up to and including April 7, 2003.

A response to the Examiner's Action is being filed on even date herewith.

Please apply the extension fee of \$465.00 under 1.17(a)(3) to Deposit Account No. 19-2553. Please apply any deficiency in the stated fee and any other required fees, and please apply any overpayment, also to Deposit Account No. 19-2553.

Respectfully submitted,

Date

April 3, 2003

*Theresa A. Lober*

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